

ABSTRACT

A susceptor that is used in semiconductor epitaxial growth and can simultaneously obtain a plurality of epitaxial films high in the uniformity is provided.

A susceptor according to the invention is a susceptor that is used in semiconductor epitaxial growth and includes a barrel type susceptor having a plurality of surfaces on an outer side of each of which a plurality of substrates can be freely disposed; and a member that has the barrel type susceptor disposed inside thereof and surfaces each of which is oppositely disposed tilting in the same direction as each of the surfaces of the barrel type susceptor. Alternatively, a susceptor according to the invention includes a barrel type susceptor having a plurality of surfaces on an inner side of each of which a plurality of substrates can be freely disposed; and a member that has the barrel type susceptor disposed at the peripheral portion thereof and surfaces each of which is oppositely disposed tilting in the same direction as each of the surfaces of the barrel type susceptor.